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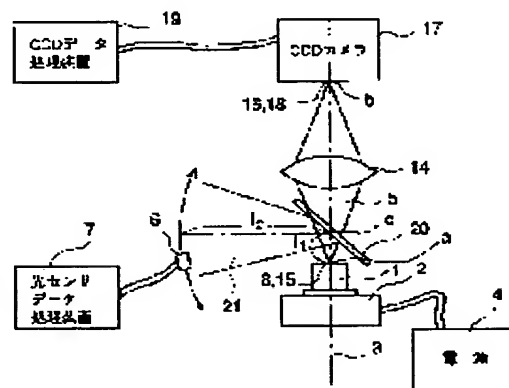
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## (54) ESTIMATION APPARATUS FOR SEMICONDUCTOR LASER

(57)Abstract:

PURPOSE: To easily and separately execute the estimation of analysis of shift of an emission position of a semiconductor laser and a shift of an angle of the beam thereof at the same time by using the same estimation system.

CONSTITUTION: A laser light 5 from a semiconductor laser 1 is converged by a condenser lens 14 and a slippage of an emission position is detected in accordance with a distance between a light spot 18 and a focusing point b16. A light intensity distribution is obtained by means of a photodetector 6 from a reflection laser light 21 reflected by a reflection plate 20. A shift of an angle of the beam is calculated from the two pieces of the data. An external laser light such as He-Ne laser is inputted from a penetration hole formed on a attachment jig 2, thereby the calibration of the apparatus is executed.



## LEGAL STATUS

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